



AN 6/2003

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Yoshikazu MIYAJIMA et al.
Application No.: 10/022,506
Filed: December 20, 2001
For: EXPOSURE APPARATUS, DEVICE
MANUFACTURING METHOD, SEMICONDUCTOR
MANUFACTURING FACTORY, AND EXPOSURE
APPARATUS MAINTENANCE METHOD

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: Examiner: R. Fuller
)
: Group Art Unit: 2851
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)
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)

Commissioner for Patents
Washington, D.C. 20231

REQUEST FOR APPROVAL OF DRAWING CHANGES

Sir:

Applicants request that the Examiner approve the changes to Figures 19A-22, 24A-24D, 25B, 26B and 28C, as shown in red on the attached sketches, enclosed in duplicate.

In Figure 19A, under "FIG. 19A," insert -- PRIOR ART --, as shown.

In Figure 19B, under "FIG. 19B," insert -- PRIOR ART --, as shown.

In Figure 20, under "FIG. 20," insert -- PRIOR ART --, as shown.

In Figure 21, under "FIG. 21," insert -- PRIOR ART --, as shown.

In Figure 22, under "FIG. 22," insert -- PRIOR ART --, as shown.

In Figure 24A, "PROJETION" should read -- PROJECTION --, as shown.

In Figure 24B, "PROJETION" should read -- PROJECTION --, as shown.

In Figure 24C, "PROJETION" should read -- PROJECTION --, as shown.

In Figure 24D, "PROJETION" should read -- PROJECTION --, as shown.

In Figure 25B, "PROJETION" should read -- PROJECTION --, as shown.

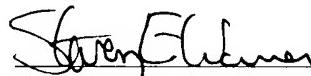
In Figure 26B, "PROJETION" should read -- PROJECTION --, as shown.

In Figure 28C, "PROJETION" should read -- PROJECTION --, as shown.

Favorable consideration is requested.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010 All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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Sir:

Transmitted herewith is an Amendment in the above-identified application.

No additional fee is required.

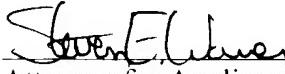
The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	60	MINUS	39	= 21	x \$9 \$18	\$ 378.00
INDEP. CLAIMS	18	MINUS	8	= 10	x \$42 \$84	\$ 840.00
Fee for Multiple Dependent claims \$140-\$280						\$ 0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$1,218.00

°Verified Statement claiming small entity status is enclosed, if not filed previously.

- A check in the amount of \$1,218.00 is enclosed.
- Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- A check in the amount of \$_____ to cover the fee for a two month extension is enclosed.
- A check in the amount of \$____ to cover the Information Disclosure Statement fee is enclosed.
- Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



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